



NIMTEC INC. ANNOUNCES ELECTRA LICENSING

NIMTEC/Japan Energy is pleased to announce that it has been licensed to supply high purity consumable components for Applied Materials' Electra™ IMP Source for Copper and Tantalum deposition.

High-purity Copper and Tantalum components (a RF coil and associated parts) are used in conjunction with a sputtering target to form copper seed layers and Ta/TaN barrier layers for advanced copper interconnect applications.

Due to the joint efforts of Applied Materials and NIMTEC/Japan Energy, high purity consumable components of the highest quality are now available directly to end users of the Electra™ IMP Source.

"With the increasing application of Electra™ IMP Ta(N) and Cu in copper interconnects by leading IC manufacturers in high volume pilot lines, Applied Materials customers require a licensed supplier of high purity consumables with an established track record and worldwide presence," said Murali Narasimhan, Global Product Manager of PVD Technologies.

"Japan Energy/NIMTEC has traditionally been an excellent partner with a high degree of focus on quality and responsiveness to our customer needs and we decided to continue this relationship for the supply of consumables for the Endura Electra™ Copper system," said Vikram Pavate, Product Manager for Electra™ Copper.

"The addition of Cu and Ta consumables for the Electra™ IMP Source is an excellent complement to our high purity sputtering targets. It also builds on our experience from supplying Ti consumables for the Applied Materials VECTRA™ IMP Source," said Kazuhiko Hosoya, Senior Marketing Manager at NIMTEC/Japan Energy.

For questions concerning the Endura Electra™ Copper System and its process capabilities, please contact Applied Materials at (408)727-5555. For questions related to high purity components for Electra™, please contact NIMTEC/Japan Energy at 1-800-646-8321 (US) or 81-3-5573-6569 (Japan).

Electra and Vectra are trademarks of Applied Materials.